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PATENT  
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S/N Unknown

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant: Gurtej Singh Sandhu et al.

Examiner: Unknown

Serial No.: Unknown

Group Art Unit: Unknown

Filed: Herewith

Docket: 303.676US2

Title: CHEMICAL VAPOR DEPOSITION OF TITANIUM

**PRELIMINARY AMENDMENT**

Commissioner for Patents  
Washington, D.C. 20231

When the above-identified patent application is taken up for consideration, please amend the application as follows:

**IN THE SPECIFICATION**

Please make the paragraph substitutions indicated in the appendix entitled Clean Version of Amended Specification Paragraph. The specific changes incorporated in the substitute paragraph are shown in the following marked-up version of the original paragraph:

The paragraph beginning on page 1, line 4 is amended as follows:

This application is a Divisional of U.S. Application No. 09/489,187, filed on January 20, 2000, which is a continuation-in-part of U.S. Application Serial No. 09/030,705, filed February 25, 1998, now issued as U.S. Patent 6,143,362 on November 7, 2000, which is hereby incorporated by reference in its entirety.

**IN THE CLAIMS**

Please cancel claims 1-43 and 46-59 after adding the following new claims.

- Sub B1*
- A1*
60. (New) An integrated circuit comprising:  
a semiconductor substrate;  
an electronic device coupled to the semiconductor substrate, the electronic device having an active region;  
an insulating layer over the active region;  
an alloy layer of a titanium alloy within a contact opening in the insulating layer, the